

00862.022167

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Shinichi HARA et al.

Application No.: 09/818,625

Filed: March 28, 2001

For: EXPOSURE APPARATUS, GAS REPLACEMENT
METHOD, SEMICONDUCTOR DEVICE
MANUFACTURING METHOD, SEMICONDUCTOR
FACTORY, AND EXPOSURE APPARATUS
MAINTENANCE METHOD

Examiner: D. Ben Esplin
Group Art Unit: 2851
February 28, 2003

The Commissioner for Patents
Washington, D.C. 20231

Sir:

Transmitted herewith is an Amendment With Petition for Extension of Time in the above-identified application.

No additional fee is required.

The fee has been calculated as shown below:

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- °Verified Statement claiming small entity status is enclosed, if not filed previously.
- A check in the amount of \$252.00 is enclosed.
- Charge \$____ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.
- Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.
- A check in the amount of \$930.00 to cover the fee for a three month extension is enclosed.
- A check in the amount of \$____ to cover the Information Disclosure Statement fee is enclosed.
- Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,



Attorney for Applicants
Steven E. Warner
Registration No. 33,326

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